



Attorney Docket No.: SAM-0256
Application Serial No.: 09/993,832
Reply to Office Action of: Sept. 22, 2004

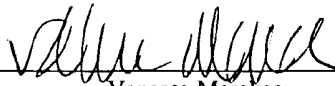
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s):	Sung-Un Kwean, <i>et al.</i>	Examiner: Ume Eronini, Lynette T.
Serial No.:	09/993,832	Group Art Unit: 1765
Filing Date:	November 6, 2001	
Title:	ETCHING GAS COMPOSITION OF SILICON OXIDE AND METHOD OF ETCHING SILICON OXIDE USING THE SAME	

CERTIFICATE OF MAILING UNDER 37 C.F.R. 1.8

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RESPONSE

Sir:

The following is in response to the Office Action dated September 22, 2004.

Remarks/Arguments begin on page 2 of this paper.